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G Vandenberghe, YC Kim, C Delvaux, KD Lucas, SJ ... - Optical Microlithography XIV [J1. CJ Proglar., Proceedings of ... - semiconductorfabtech.com

... for memory applications) or scatter bar **OPC** and alternating ... Also, issues such as the **aberration** sensitivity and ... as there is almost no **higher order** captured by ...

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T Brunner, D Corliss, S Butt, T Wiltshire, CP ... - Journal of Microlithography, Microfabrication, and ..., 2006 - link.aip.org

... (The accuracy impact of ignoring the wavelength dependence of **higher order aberrations**,

such as coma, was not ... Impact of Focus Blur on Lithography and **OPC**. ...

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AH Smith, J Bendik, RO Hunter - 2005 - freepatentsonline.com

... and where $O(ax)$ represents **higher order aberrations**, each of ... overlay mark error, source/**aberration** coupling ... for example, "Resolution Enhancement with **OPC/PSM**", F ...

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FE Gennari - 2006 - freepatentsonline.com

... of the **Aberration Pattern-Matching OPC** Process," SPIE ... represent a combination of **aberrations** present in the ... is a tradeoff; using **higher order** primitives vastly ...

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[Eigen decomposition based **OPC** model](#)

X Shi, RJ Socha, T Laidig, DVD Broeke - 2005 - freepatentsonline.com

... [0012] There are several ways to develop and implement model **OPC**, such as ... to an air/resist interface, $W(\alpha, \beta)$ is an **aberration** function, Δ

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[Lens **Aberration** Aware Placement for Timing Yield](#)

AB Kahng, CH Park, P Sharma, Q Wang - visicad.ucsd.edu

... Using industry **OPC** recipes, **aberration** parameters, and design testcases, we show that the variation in timing due to lens **aberration** can be significant. ...

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[Modification of a projection imaging system with a non-circular aperture and a method thereof - group of 3 »](#)

BW Smith - US Patent 6,541,750, 2003 - Google Patents

... 22 and corner performance is improved via illumination with a square shaped aperture 22 and **OPC** as described above. 5The influence of **aberrations** on imaging is ...

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